



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Hitoshi YAMADA, et al.

Application No.: 10/076,333

Group Art Unit: 2817

Confirmation No.: 2817

Filed: February 19, 2002

Examiner: D. Dong

For: GAS DISCHARGE TUBE AND METHOD FOR FORMING ELECTRON EMISSION
LAYER IN GAS DISCHARGE TUBE

RESPONSE TO RESTRICTION REQUIREMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action mailed February 18, 2003, applicants elect Claims 4-11
of Group II, without traverse.

Respectfully submitted,

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Date: March 4, 2003

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